

# CHILLAX – developing a xenon-doped dual-phase argon detector for rare event searches

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# Outline

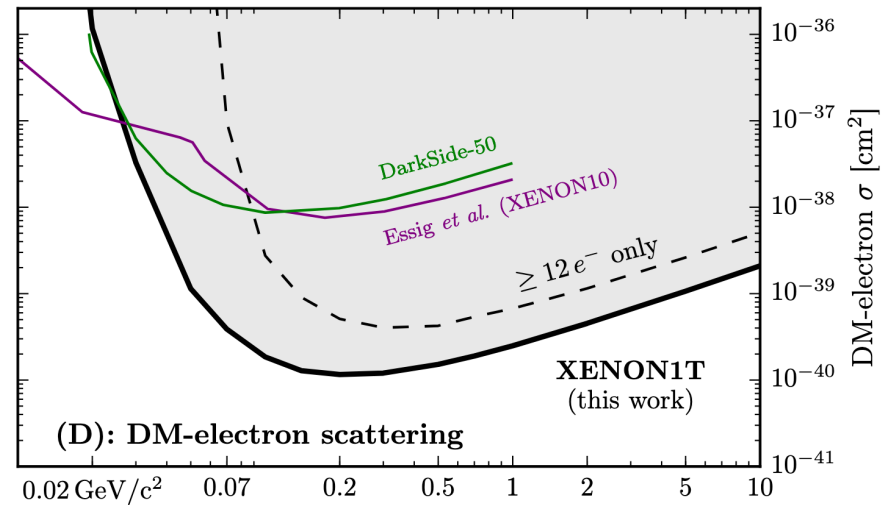
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- Introduction
  - Physics motivation for CHILLAX
  - Benefits of xenon doping in dual-phase argon detectors
- CHILLAX detector development
  - Xenon doping cryogenics
  - CHILLAX design features
  - Preliminary xenon doping test results
  - Direct VUV light readout with SiPMs
- Conclusion and outlook

# Low-mass dark matter searches

Liquid argon and xenon ionization detectors also lead low-mass dark matter searches

- Extremely low background rates in the keV energy region
  - $< 1$  event/ton/keV/day in xenon
  - $\sim 0.1$  event/kg/keV/day in argon
- Large detector mass
- Low energy threshold
  - Single ionization electron sensitivity
  - $< 1$  keV threshold in Ionization only mode
  - $\ll 1$  keV threshold assuming Migdal effect



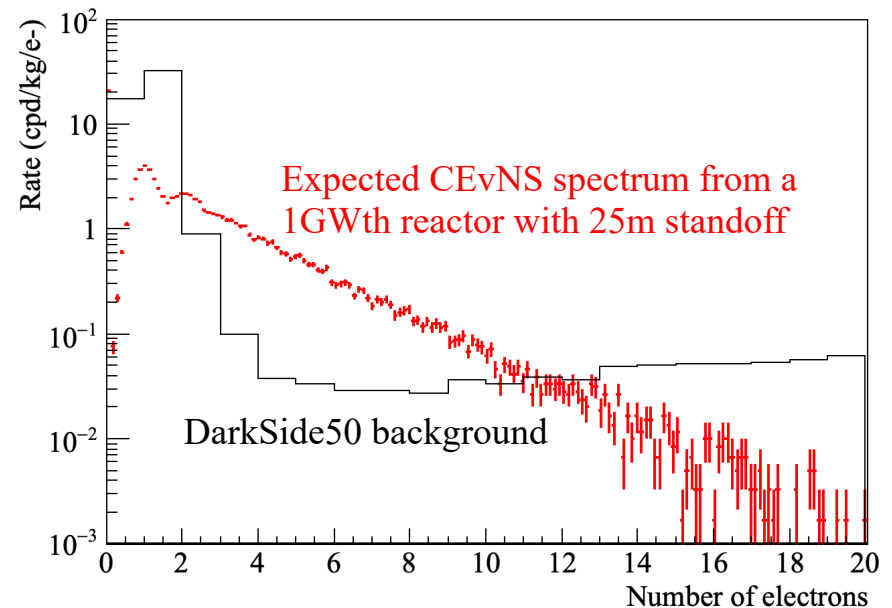
# CEvNS detection with noble liquids

Coherent Elastic neutrino-Nuclear Scatter (CEvNS) is a rare process analogous to low-mass WIMP dark matter interactions

- A new probe into BSM physics
- Complementary to IBD-based reactor monitoring programs

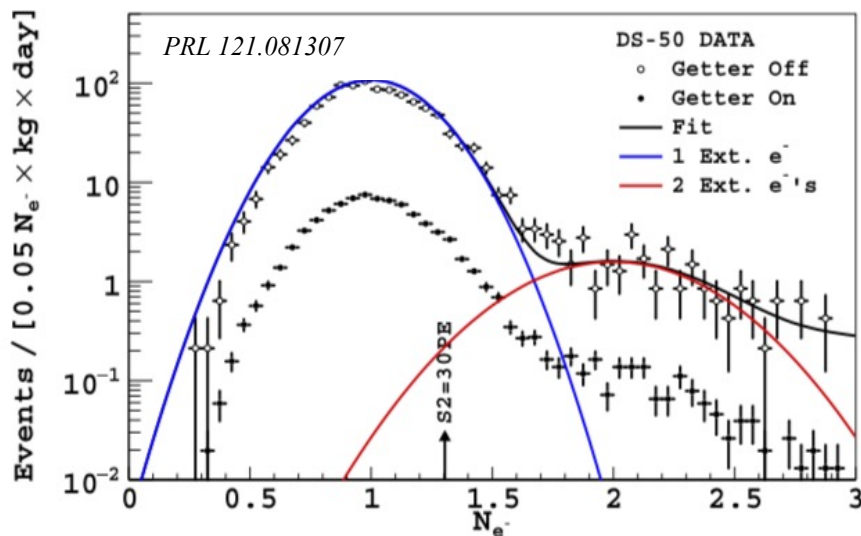
Liquid argon and xenon ionization detectors are good candidates for CEvNS detection

- Sufficiently low energy threshold
- Low background rate
- Large target mass achievable

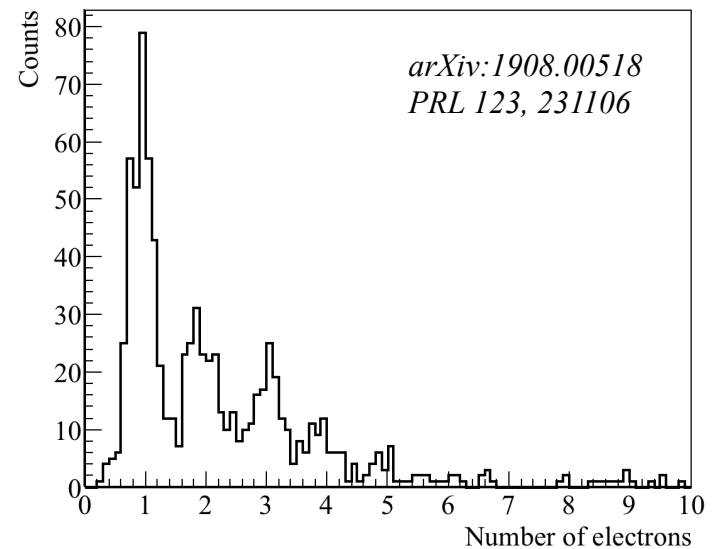


# Can one combine advantages of Ar and Xe?

- Argon is a preferred target for kinetic coupling to neutrinos and low-mass DM
- Argon detectors may have a lower ionization background rate
  - Impurity outgassing is a main source for few-electron background (LAr is colder)
  - Unextracted electrons from liquid into gas is another (reduced in LAr)
- Xenon detectors have outstanding energy resolution in the few-electron region
  - Longer wavelength light reduces complexity of signal collection



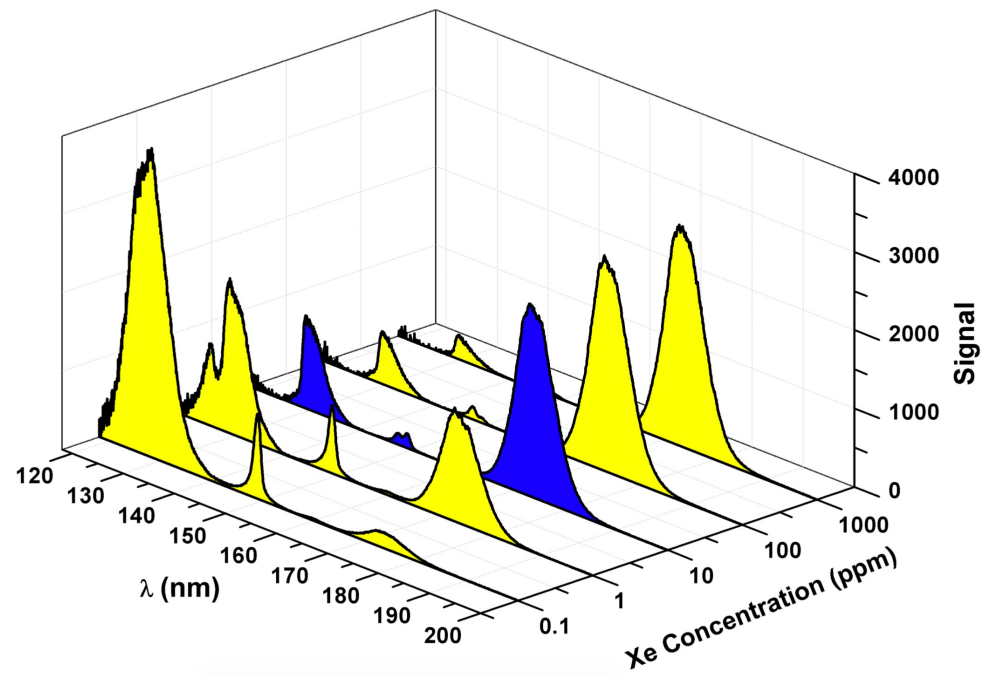
Single and double electron spectrum in DarkSide50



Few-electron spectrum (400eV Xe recoils) in LLNL XeTPC

# Xenon-doping in liquid argon (as is usually discussed)

- Low-concentration xenon doping in liquid argon is well studied for “wavelength shifting” of argon scintillation light
  - Energy transfer from Ar\* to Xe
  - Wavelength shifting of 128nm light
  - Longer wavelength, shorter decays
  - 10ppm xenon in LAr almost completes the “wavelength shifting” process
- This technique may have significant application in large LArTPCs such as DUNE

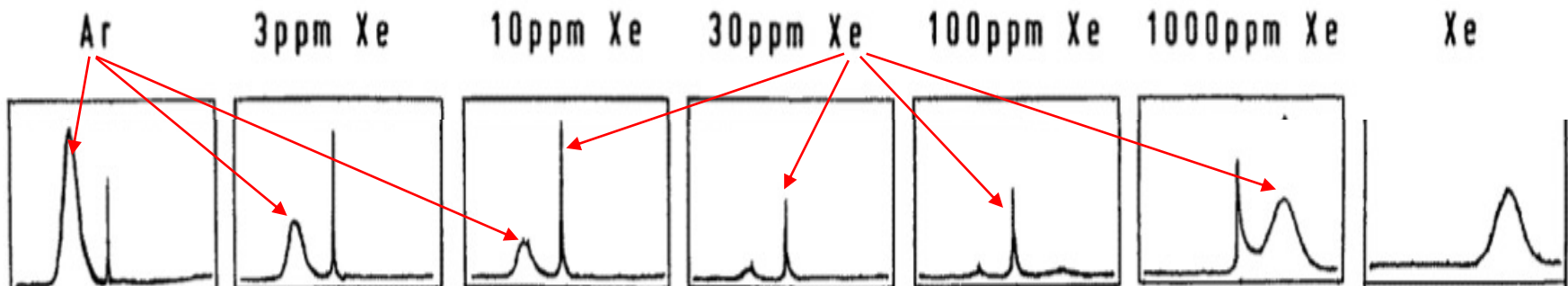
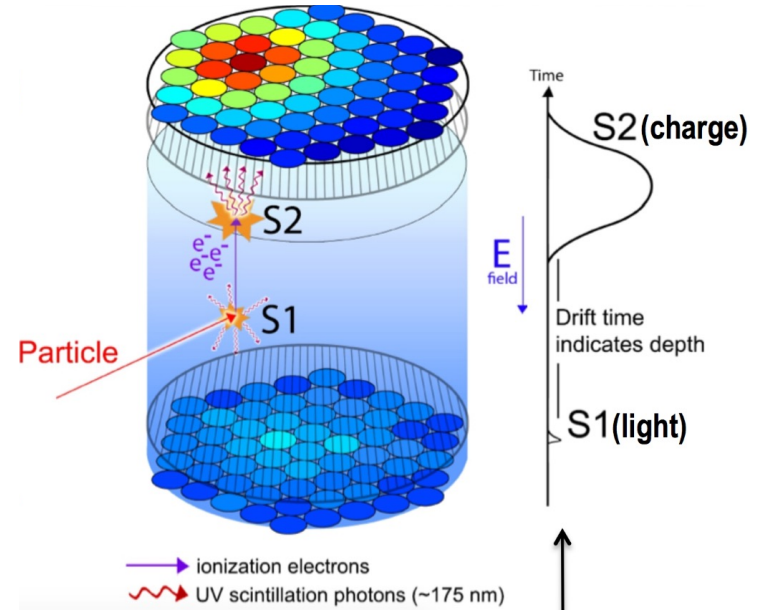


Spectra of scintillation light emission in liquid argon-xenon mixtures  
*A. Neumeier et al., Europhys. Lett. 109 12001 (2015)*

# Xenon-doping for better ionization detection?

Xenon doping may enhance electron signal amplification in a dual-phase argon detector

- Electron signals are amplified through electroluminescence in the gas phase
- 10s of ppm xenon in gaseous argon can shift a large fraction of argon electroluminescence to longer (xenon) wavelengths
  - Possibly **higher photon yield**
  - Longer wavelength → **easier detection**
  - Shorter decay → **improved timing**

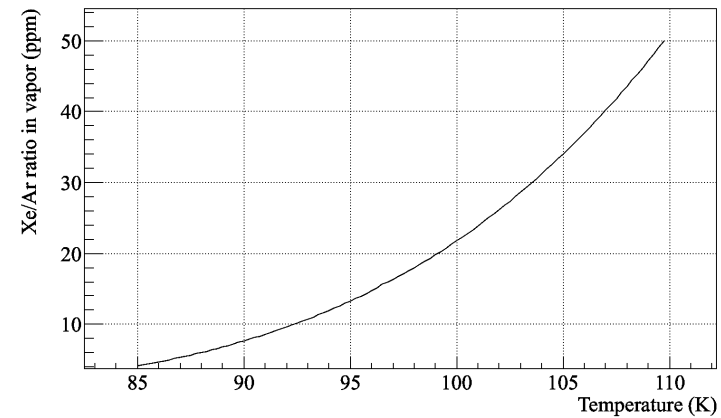
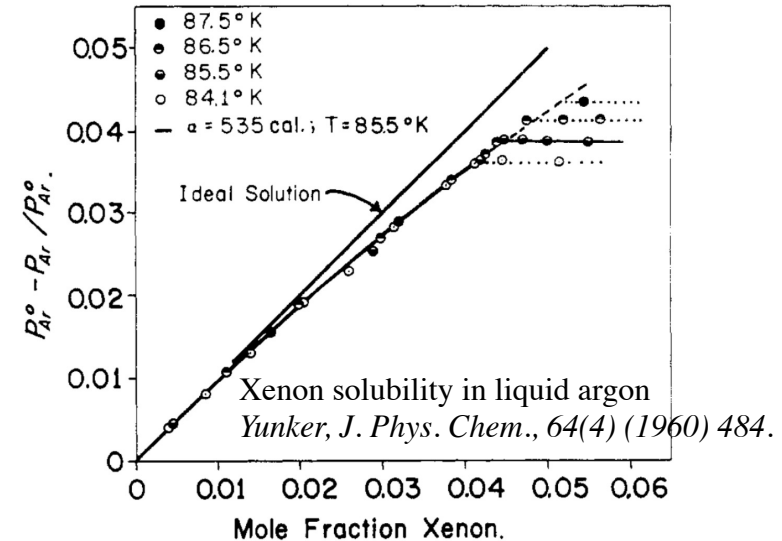


*T Efthimiopoulos et al 1997 J. Phys. D: Appl. Phys. 30 1746*

# Xenon-doping for better ionization detection?

Can we get 10s of ppm gaseous xenon in a dual-phase argon detector?

- Xenon has high solubility in liquid argon
  - 4.5% by mole fraction at 87.5K
  - 7% by mole fraction at 95K (extrapolation)
- Xenon has appreciable vapor pressure at liquid argon temperature
  - 1e-4 bar at 87.5K, and 5e-4 bar at 94K
  - A few percent of xenon doping in the liquid may give 10s of ppm of xenon in the gas based on Raoult's law
  - Chemical potential argument predicts higher xenon concentration in gas



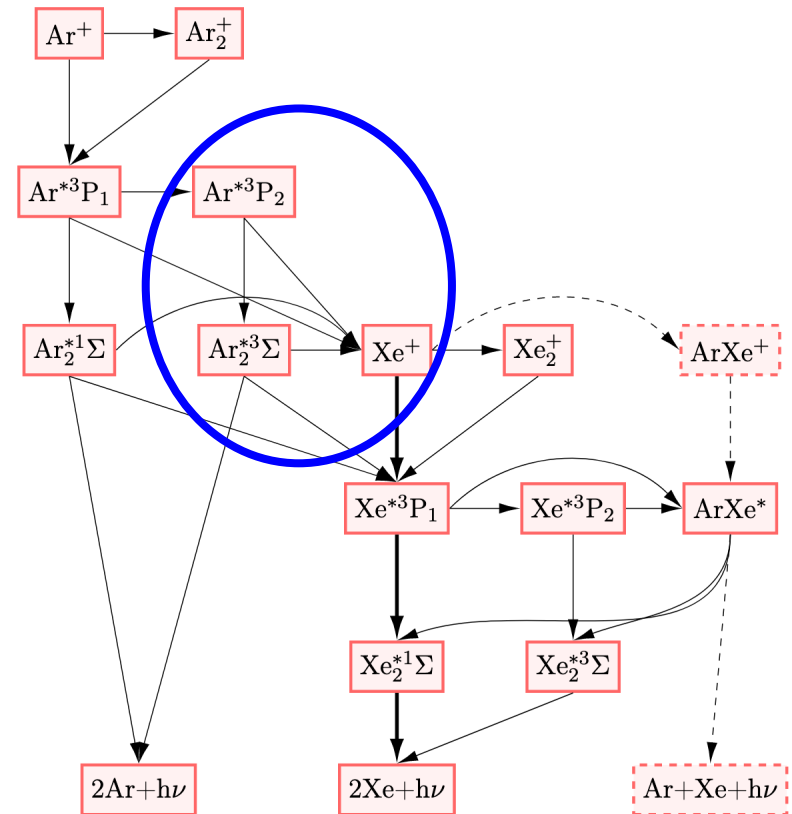
Calculated Xe concentration in a dual-phase argon detector with 4% xenon doping (Raoult's law/ideal solution)



# Xenon-doping to boost ionization signal?

For detection of small ionization signals, xenon doping may lead to more ionization electrons per energy deposition

- Some Ar excitation states have higher energy levels than Xe ionization
- Penning ionization of argon excitations could lead to xenon ionization and additional electrons
- May require high electric field to observe significant effect
- Effect to be confirmed experimentally



Energy transfer processes in xenon-doped argon  
*C. Galbiati et al 2021 JINST 16 P02015*

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# Technical challenges of xenon doping

High-concentration xenon doping poses serious technical challenges

- How to mix a lot of xenon into liquid argon in a reasonable period of time?
  - ~100ppm of xenon may be introduced to argon gas stream in a typical condensation scheme
  - 1% doping of xenon takes ~100 times more time than the condensation of argon

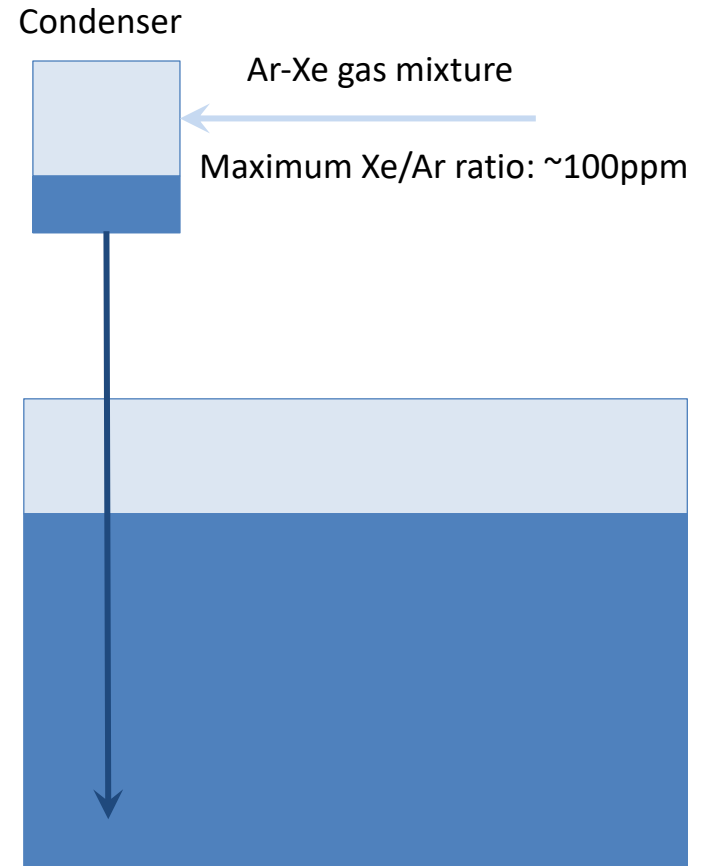


Illustration of a typical gas condensation scheme for dual-phase noble liquid detectors

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  - 1% doping of xenon takes ~100 times more time than the condensation of argon
- How to circulate the Ar-Xe mixture to maintain liquid purity for detector operation?
  - A distillation scenario is created when the liquid mixture turns into gas
  - **Where liquid boils, ice forms!**

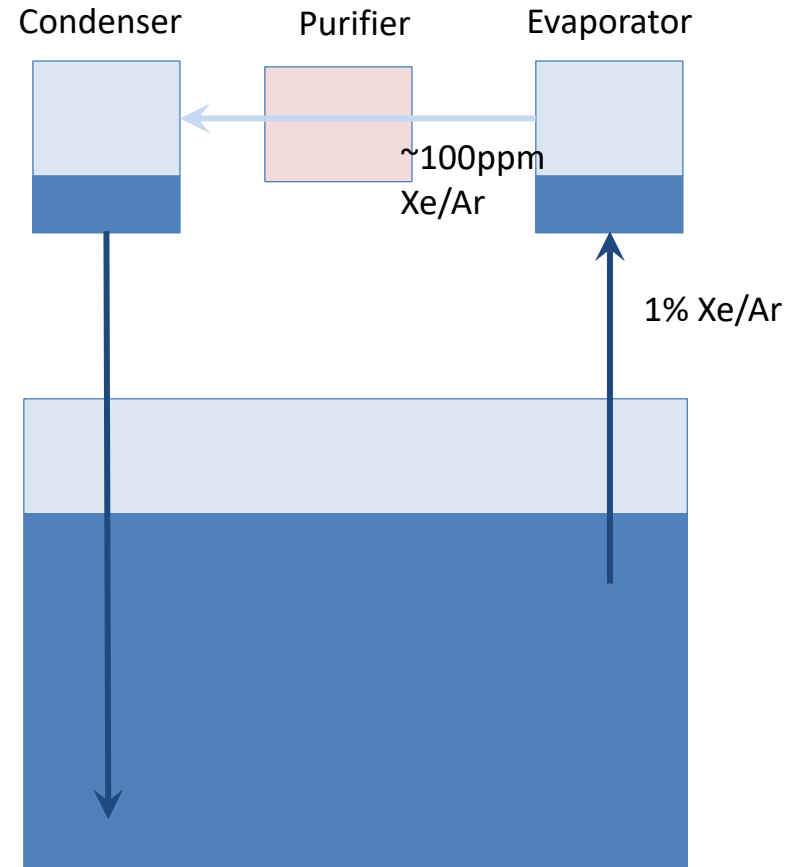
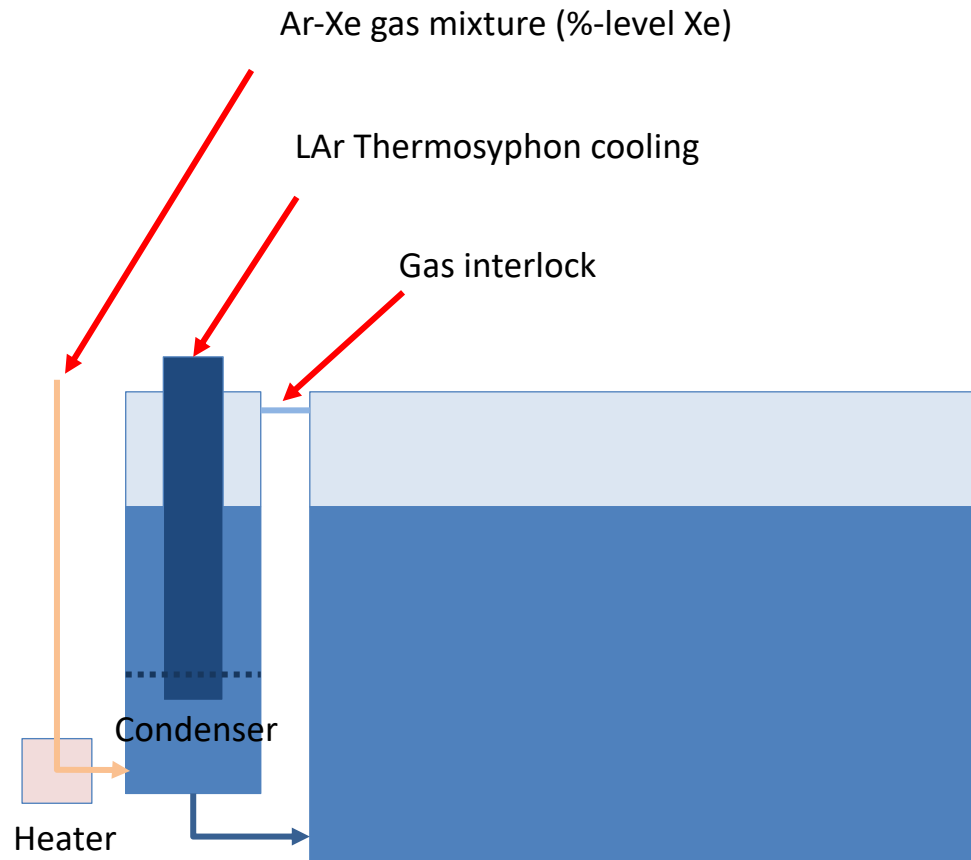


Illustration of a typical gas circulation scheme for dual-phase noble liquid detectors

# Xenon delivery in CHILLAX

To obtain %-level xenon doping, CHILLAX adopts a different condensation scheme

- Introduce 1-2% Xe-Ar mixture gas directly into liquid argon
- Full xenon capture in liquid (ice can dissolve if it forms)
- Direct cooling applied to liquid argon (through thermosyphon) next to detector
- Pre-heating Xe-Ar gas before entrance to condenser



# Xenon delivery in CHILLAX

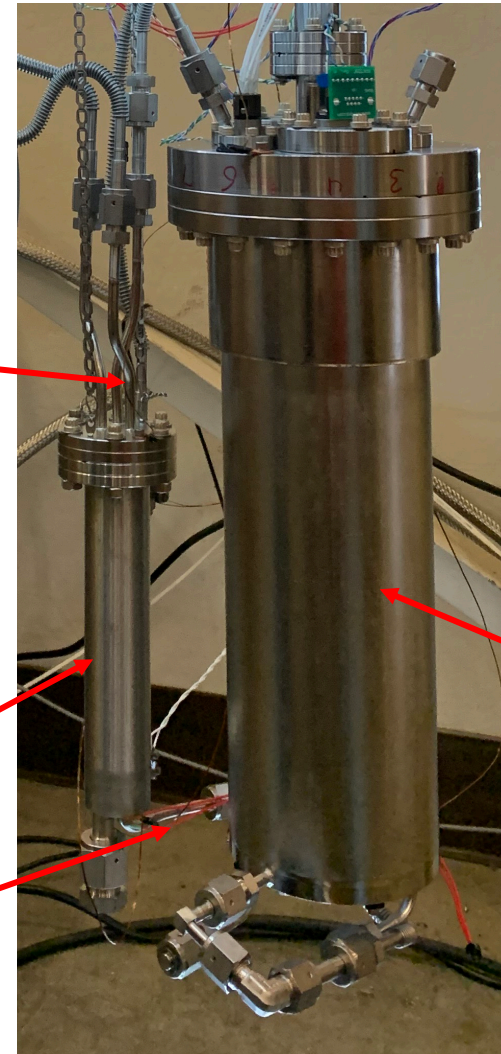
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Thermosyphon  
Input/output

LAr condenser

LAr delivery  
to detector

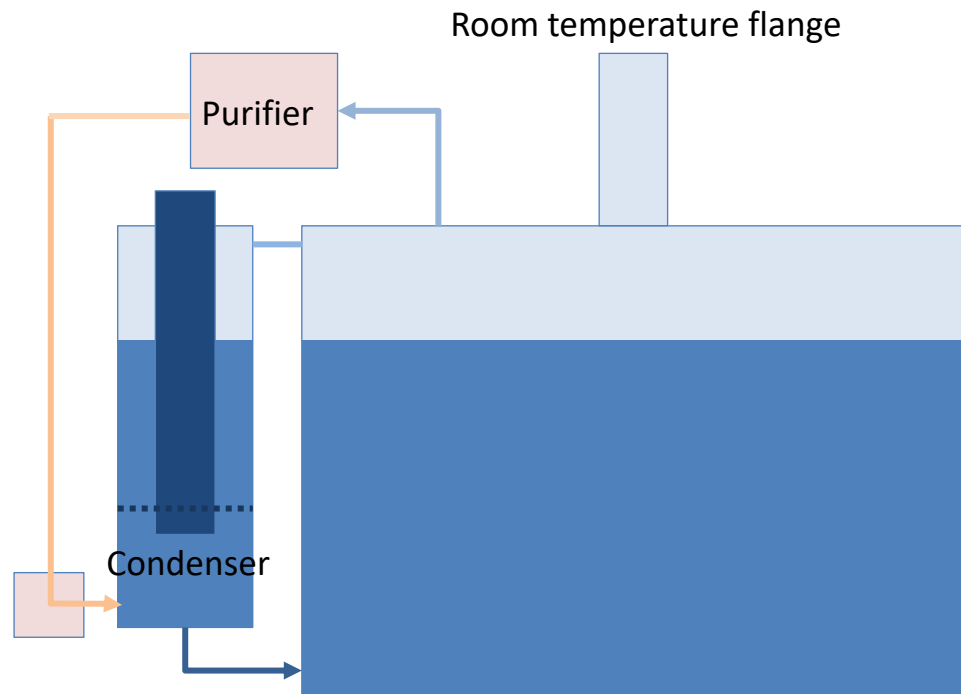


Detector

# Circulation-purification in CHILLAX

Continuous circulation and purification are needed to keep the target clean

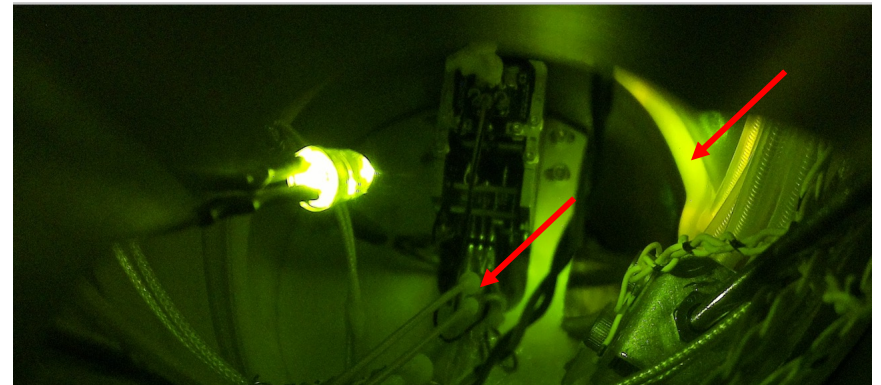
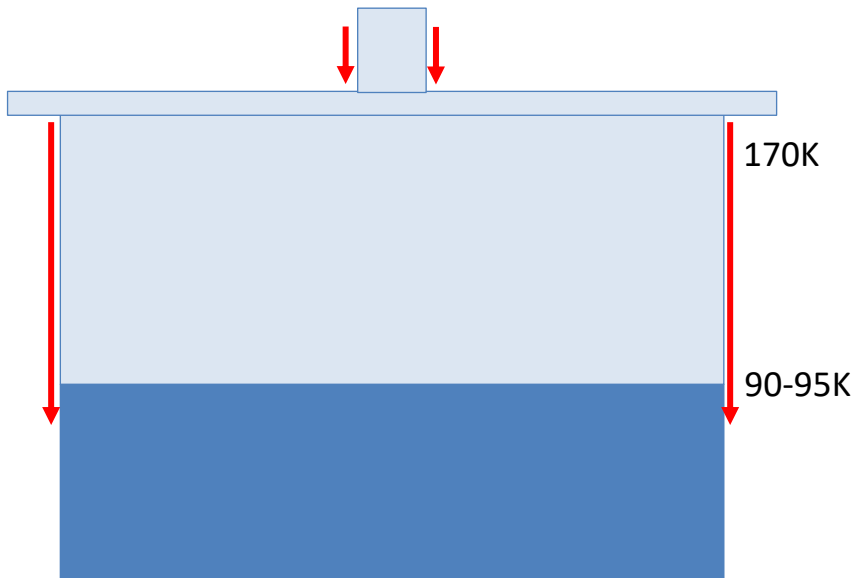
- Ideally, we would move liquid through purifier
  - No phase transition/distillation
  - No xenon congregation
- We are currently testing circulating gas from detector volume
  - No xenon congregation outside detector argon volume
  - Liquid convection could prevent xenon ice forming



# Retaining xenon in liquid mixture

Thermal leaks into liquid mixture will cause boiling and distillation

- Detector support structure is mounted on room temperature flanges
- Heat traveling down detector can cause liquid next to detector wall to boil and local xenon concentration to increase
  - Liquid splashed/capillary-drawn onto walls boils off and leaves behind xenon ice
  - Xe-saturated argon might produce saturated Xe gas that can condense on wall surfaces near by

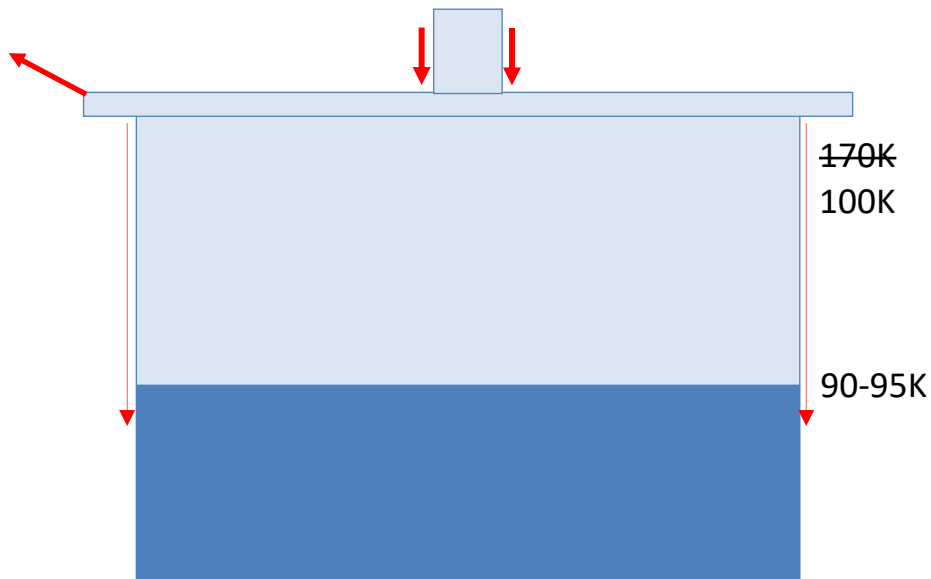




# Retaining xenon in liquid mixture

We added a thermal link to the cryocooler to intercept heat leak down the support

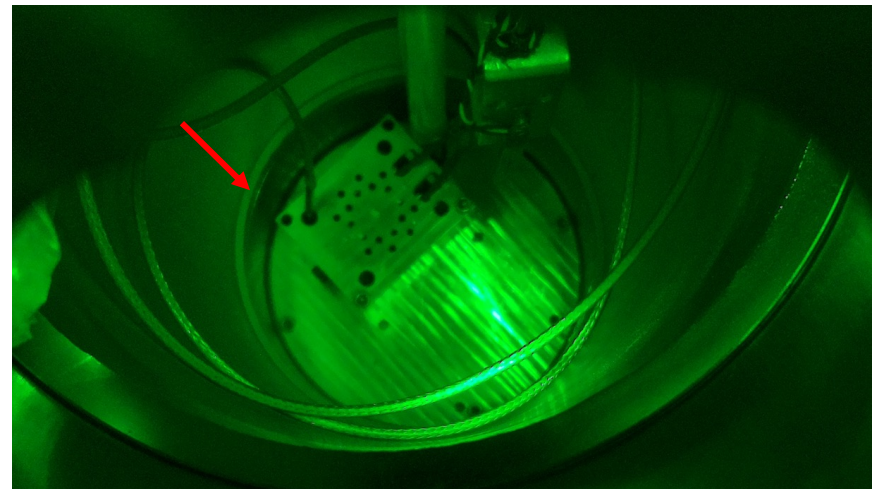
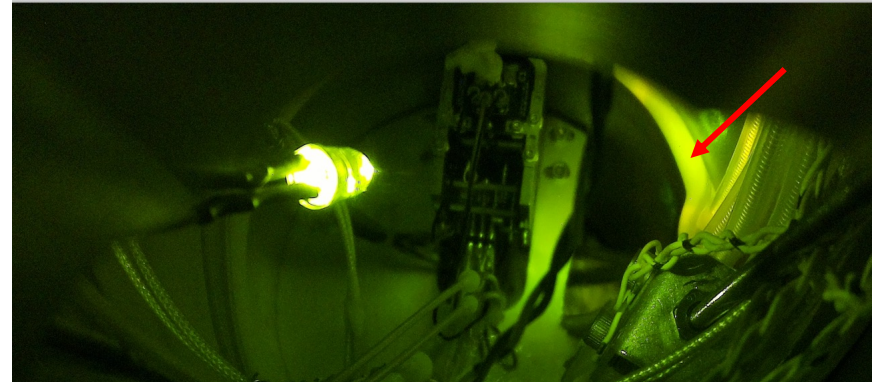
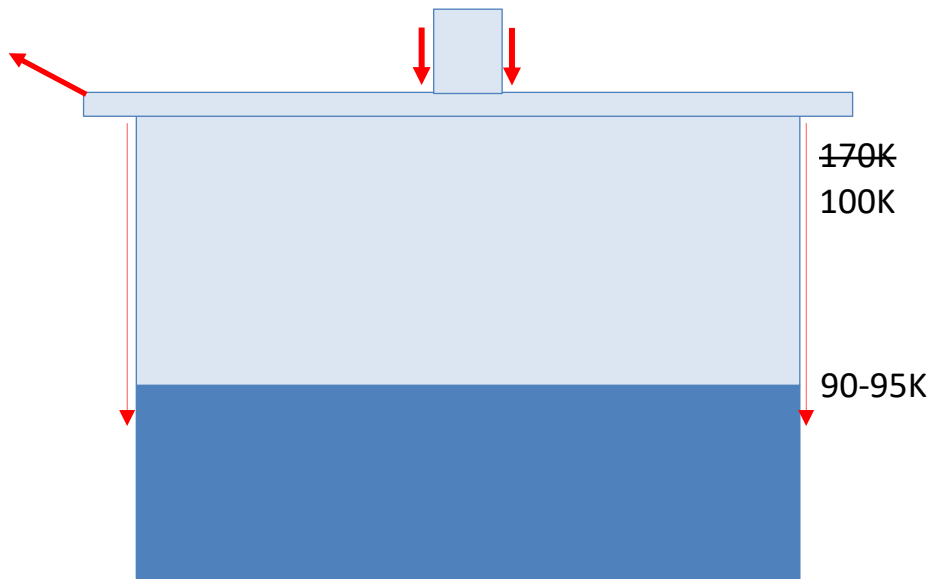
- Detector flange cooled to  $\sim 100\text{K}$  while liquid mixture stays at  $90\text{-}95\text{K}$
- Xenon ice forming is much slowed
- Will add thermosyphon for stronger cooling (possibly produce Ar reflux on walls)



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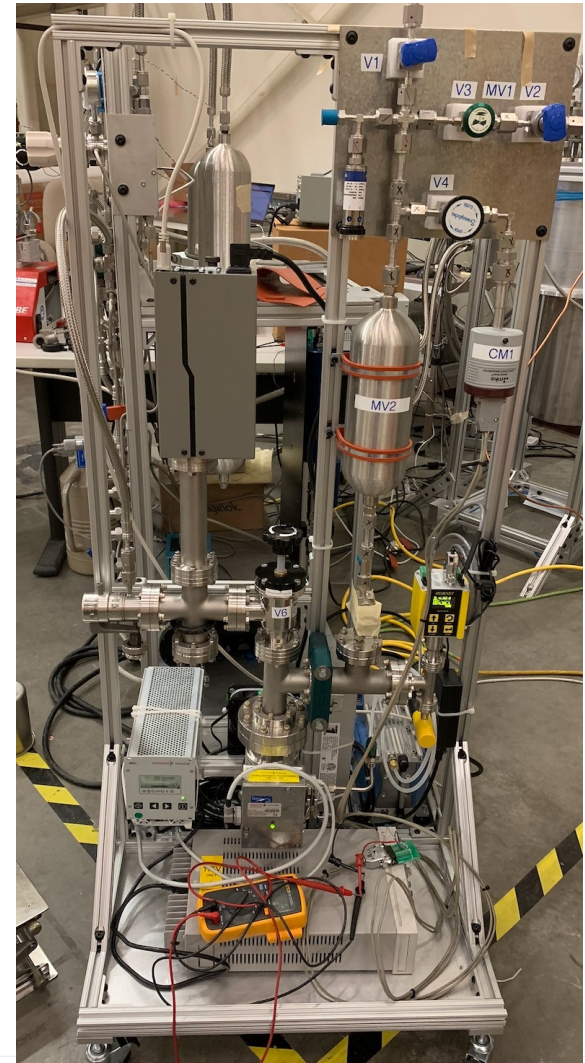
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# Xenon concentration measurement in the gas

To gain benefits of xenon doping for electron signal amplification, we need 10s of ppm Xe/Ar in the gas

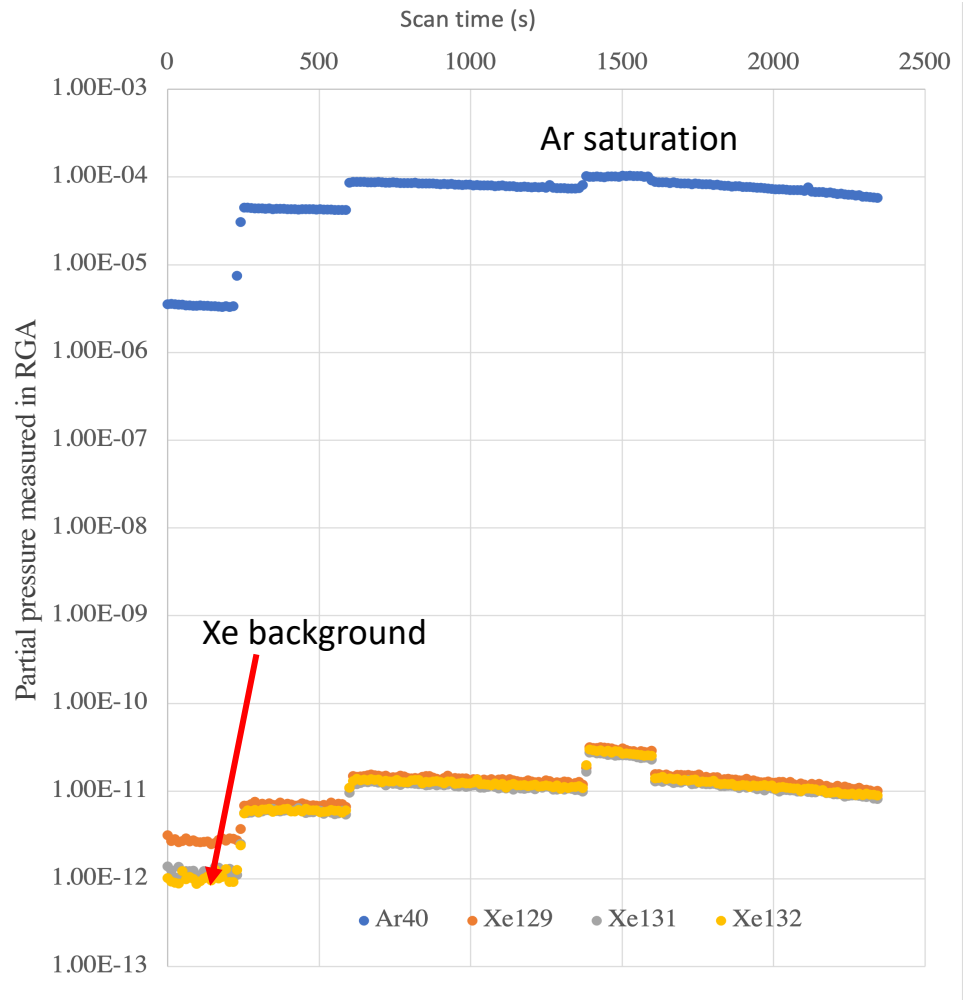
- Goal is to achieve ~30-50ppm Xe/Ar
- Gas composition sampled with RGA200
- Gas dilution through volume expansion, pressure bleeding, pinhole and leak valve control
- Ar-Xe gas mixture in the ppm level can be prescribed for system calibration



# CHILLAX Sampling system calibration

## RGA scan of prescribed Ar-Xe mixture

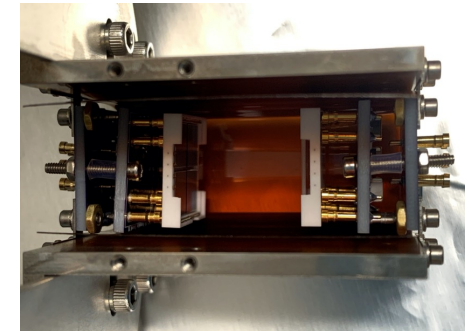
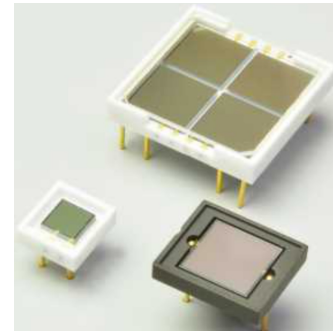
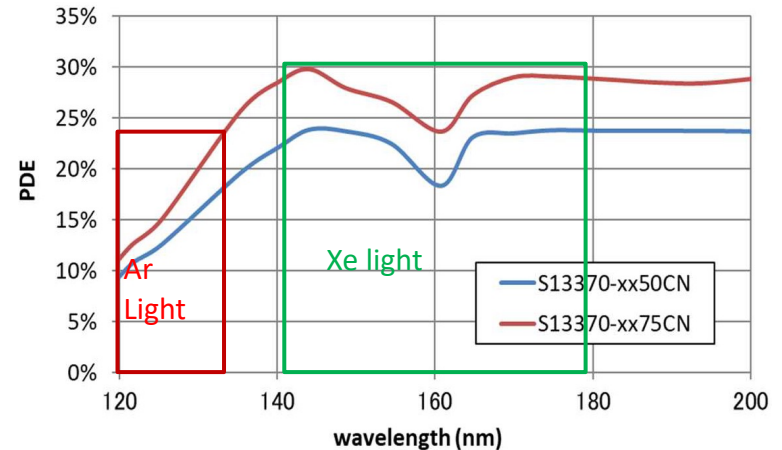
- Sample contains 2ppm Xe/Ar
- Scan used both FC and CEM
- RGA measured  $\sim 0.6$  ppm
- Complete calibration curve under development
- We observed gaseous xenon concentration in the 10s of ppm region for liquid doping of  $\sim 1-2\%$
- High voltage system to measure electroluminescence gain in preparation



# CHILLAX detection of VUV photons

At ~10s of ppm Xe/Ar ratio in the gas, electroluminescence signal may contain  $\text{Ar}^*_2$ ,  $\text{ArXe}^*$  and possible  $\text{Xe}^*_2$  light

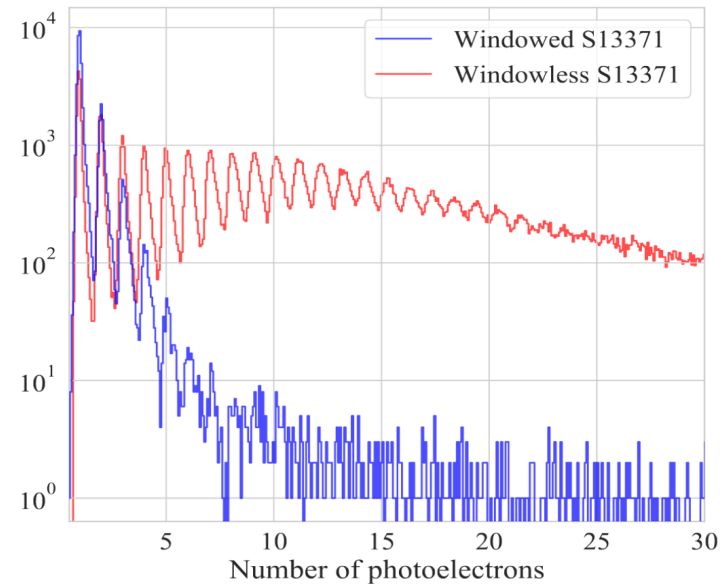
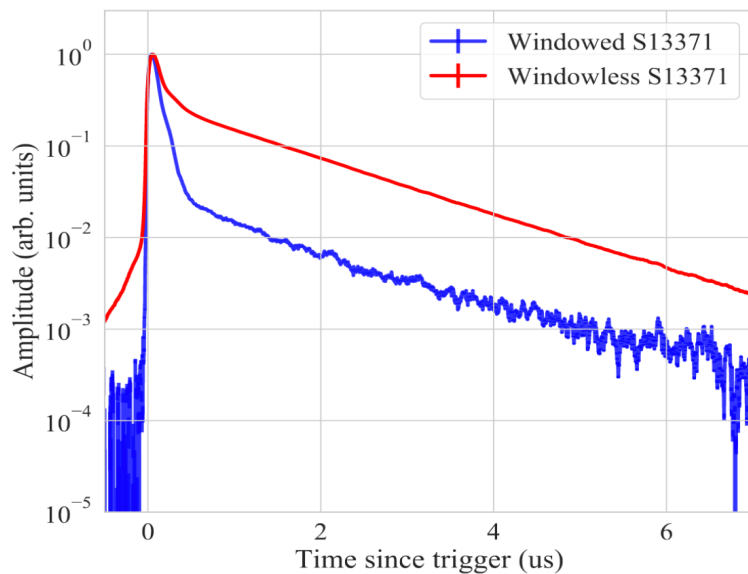
- Light detection system needs sensitivity to 128, 147 and 175nm light
- Hamamatsu VUV4 SiPMs are chosen based on their specs
- In-house, onboard, cold amplifiers were built for two types of VUV4 SiPMs (with quartz window and without)
- SiPM modules deployed in CHILLAX (both pure argon and argon-xenon mixture)



# Direct detection of 128nm light

We designed control experiments using VUV4 SiPMs with and without quartz windows (160nm cutoff) to verify direct UV sensitivity

- VUV4 SiPMs with quartz window detected < 1% of light compared to windowless ones
- VUV4 SiPMs with quartz window observed weak argon triplet scintillation component

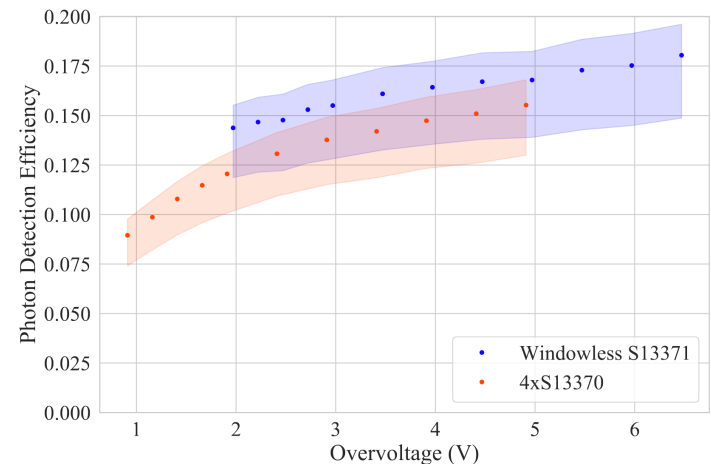
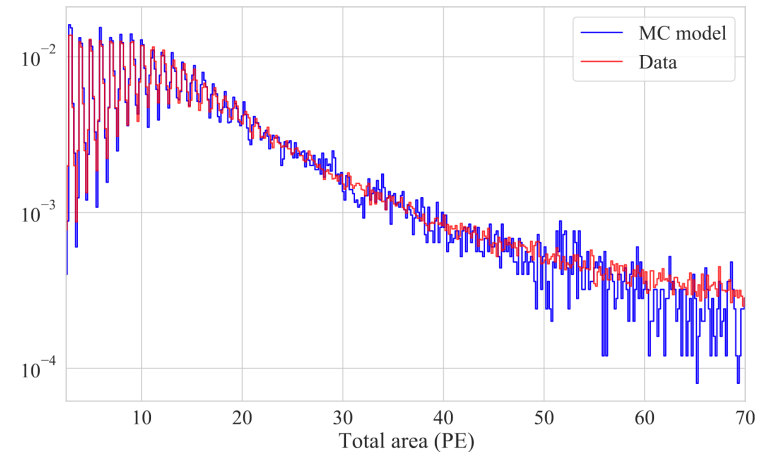


Average SiPM waveforms (left) and energy spectra measured with windowed (blue) and windowless (red) VUV SiPMs for  $^{241}\text{Am}$  radiation in pure liquid argon, confirming 128nm sensitivity

# Detection efficiency for 128nm light

We measured appreciable PDE values for VUV4 SiPMs at 128nm

- MC simulation tracks data well
- ~15% PDE at 128nm
- Previous characterizations of VUV4 SiPMs at 175nm reported lower than quoted PDE (possibly due to quartz window)
- VUV4 SiPMs are suitable for direct liquid argon light detection!
- Publication arXiv:2202.02977, accepted by JINST



Fitted SiPM spectra for pure argon scintillation (top) and the evaluated SiPM PDE (bottom)

# Conclusion and Outlook

- Xenon doping in liquid argon detectors has promising benefits
- High-concentration xenon doping, despite challenges, can substantially improve performance of dual-phase argon detectors
- CHILLAX has demonstrated preliminary success in introducing and maintaining high xenon concentration in liquid argon
- We have demonstrated direct 128nm sensitivity of VUV4 SiPMs
- We are ready to measure the effects of xenon-doping on electron signal amplification in a dual-phase configuration
- We will study possible increase of ionization yield of argon by xenon doping
- A lot of interesting results to expect this year -- stay tuned



# Relevance to low-level xenon doping efforts

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- A liquid argon body doped with xenon is not stable
- Where liquid boils, ice can form
- A uniform temperature profile throughout the cryogenic system is crucial
- Small thermal leaks can cause xenon to deplete from active volume
- Even in systems with low xenon concentration, slow thermal processes could lead to xenon non-uniformity over time
- Further discussions and collaboration on xenon doping studies will be welcomed!



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